



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Malozemoff et al.

Art Unit : 2831

Serial No. : 10/624,026

Examiner : Unknown

Filed : July 21, 2003

Title : HIGH TEMPERATURE SUPERCONDUCTING DEVICES AND RELATED METHODS

Commissioner for Patents  
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Applicant submits copies of all foreign patent documents, foreign patent applications, and other documents listed on the attached form PTO-1449. In accordance with the U.S. Patent and Trademark Office Official Gazette Notice dated August 5, 2003, copies of U.S. patents and published U.S. applications listed on the attached form PTO-1449 are not included.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 2-9-2004

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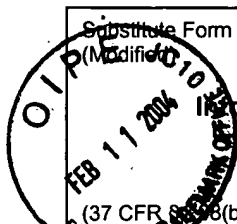
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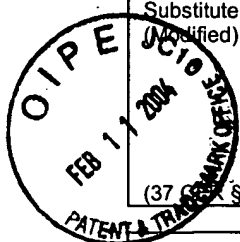
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 Substitute Form PTO-1449 (Modified) <b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR 1.102(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. <b>05770-198001</b>	Application No. <b>10/624,026</b>
	Applicant <b>Malozemoff et al.</b>		
	Filing Date <b>July 21, 2003</b>	Group Art Unit <b>2831</b>	

**U.S. Patent Documents**

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	6,256,521 B1	07/03/2001	Lee et al.			
	AB	6,172,009 B1	01/09/2001	Smith et al.			
	AC	6,077,344	06/20/2000	Shoup et al.			
	AD	6,027,564	02/22/2000	Fritzemeier et al.			
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	AG	5,968,877	10/19/1999	Budai et al.			
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	AAA	4,956,340	09/11/1990	Kimura et al.			

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EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



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<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 C.F.R. § 1.98(b))		Applicant Malozemoff et al.	
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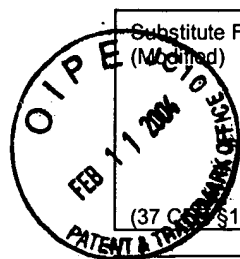
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	ABB	4,882,312	11/21/1989	Mongro-Campero et al.			
	ACC	4,859,652	08/22/1989	Block			
	ADD	4,659,973	04/21/1987	Stich			
	AEE	4,442,396	04/10/1984	Hucker			
	AFF	3,985,281	10/12/1976	Diepers et al.			
	AGG	3,763,552	10/09/1973	Brown et al.			

### Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AHH	WO 01/98076	12/27/2001	PCT				
	AII	WO 99/35083	07/15/1999	PCT (abstract only)				
	AJJ	WO 99/25908	05/27/1999	PCT				
	AKK	WO 99/16941	04/08/1999	PCT				
	ALL	WO 99/17307	04/08/1999	PCT				
	AMM	WO 98/58415	12/23/1998	PCT				
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	AOO	WO 97/05669	02/13/1997	PCT				
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	ARR	0 506 528 B1	09/30/1992	EPO				X
	ASS	WO 92/05591	04/02/1992	PCT				
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	AVV	0 387 525 A1	09/19/1990	EPO				X
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	AXX	0 308 869 A3	03/29/1989	EPO				
	AYY	63310366	12/19/1988	Japan (abstract only)				

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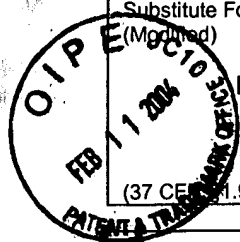
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AZZ	57075564	05/12/1982	Japan (abstract only)				

### Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AAAA	"DRY ETCHING for VLSI FABRICATION", vol. 1, eds. S. Wolf and R.N. Tamber, Lattice Press, Sunset Park, CA, pp 539-574 (1986).
	ABBB	"FABRICATION OF HIGH TEMPERATURE SUPERCONDUCTING FILMS USING PERFLUORO-ORGANOMETALLIC PRECURSORS", IBM Technical Disclosure Bulletin, Vol. 32, No. 5B, October 1989, p 241.
	ACCC	Apicella et al., "The Effects of Surface Contamination On The Biaxially Textured Substrate For YBCO Thick Film Deposition", International Journal of Modern Physics B, Vol. 13, Nos. 9 & 10 (1999) pp 997-1004.
	ADDD	Beach et al., "SOL-GEL SYNTHESIS OF RARE EARTH ALUMINATE FILMS AS BUFFER LAYERS FOR HIGH T <sub>c</sub> SUPERCONDUCTING FILMS", Mat. Res. Soc. Symp. Proc. Vol. 495, 195, pp 263-270.
	AEEE	Boffa et al., "Laser-ablation deposition of CeO <sub>2</sub> thin films on biaxially textured nickel substrates", Physica C 312 (1999) 202-212.
	AFFF	Gupta, et al., "Superconducting oxide films with high transition temperature prepared from metal trifluoroacetate precursors," 320 Applied Physics Letters 52 (1988) No. 24, New York, NY, USA
	AGGG	Hammerl et al., "Possible solution of the grain-boundary problem for applications of high-T <sub>c</sub> superconductors", Appl. Phys. Lett., Vol. 81, No. 17, 2002).
	AHHH	He et al., "Deposition of biaxially-oriented metal and oxide buffer-layer films on textured Ni tapes: new substrates for high-current, high-temperature superconductors", Physica C, 275 (1997) 155-161.
	AIII	He et al., "Growth of biaxially oriented conductive LaNiO <sub>3</sub> buffer layers on textured Ni tapes for high-T <sub>c</sub> -coated conductors", Physica C 314 (1999) 105-111.
	AJJJ	Koster et al., "Influence of the surface treatment on the homoepitaxial growth of SrTiO <sub>3</sub> ", Materials Science and Engineering B56 (1998) 209-212.
	AKKK	Lee et al., "Alternative Buffer Architectures for High Critical Current Density YBCO Superconducting Deposits on Rolling Assisted Biaxially-Textured Substrates", Jpn. J. Appl. Phys. Vol. 38 (1999) Pt. 2, No. 2B, pp 178-180.
	ALLL	McIntyre et al., "Epitaxial nucleation and growth of chemically derived Ba <sub>2</sub> YCu <sub>3</sub> O <sub>7-x</sub> thin films on (001) SrTiO <sub>3</sub> ", Journal of Applied Physics, 77 (1995) 15 May, No. 10, pp 5263-5272.
	AMMM	McIntyre et al., "Effect of growth conditions on the properties and morphology of chemically derived epitaxial thin films of Ba <sub>2</sub> YCu <sub>3</sub> O <sub>7-x</sub> on (001) LaAlO <sub>3</sub> ", J. Appl. Phys. 71 (4), 15 February 1992, pp 1868 - 1877.
	ANNN	Moore et al., "Sol-Gel Processing of Y <sub>1</sub> Ba <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> Using Alkoxide Precursors: Two Systems Yielding High Degrees of Thin Film Orientation and Crystal Growth", Materials Letters, Vol 7, No. 12, March 1989, pp 415-424.

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	A000	Paranthaman et al., "Growth of biaxially textured RE <sub>2</sub> O <sub>3</sub> buffer layers on rolled-Ni substrates using reactive evaporation for HTS-coated conductors", Supercond. Sci. Techno. 12(1999) 319-315. Printed in the UK.
	APPP	Qing He, D.K. et al., "Deposition of biaxially-oriented metal and oxide buffer-layer films on textured Ni tapes: new substrates for high-current, high-temperature superconductors", <i>Physica C</i> , Vol. 275 (1997) pp. 155-161
	AQQQ	Rupich et al., "Growth and Characterization of Oxide Buffer Layers for YBCO Coated Conductors", IEEE TRANSACTIONS ON APPLIED SUPERCONDUCTIVITY, Vol. 9, No. 2, June 1999, pp 1527-1530.
	ARRR	Rupich et al., "Synthesis of superconductors from soluble metal oxo alkoxide precursors", J. Mater. Res., Vol. 8, No. 7, Jul 1993, pp 1487-1496.
	ASSS	Sheth et al., "Bench Scale Evaluation of Batch Mode Dip-Coating of Sol-Gel LaAlO <sub>3</sub> Buffer Material", IEEE TRANSACTIONS ON APPLIED SUPERCONDUCTIVITY, Vol. 9, No. 2, June 1999, pp 1514 - 1518.
	ATTT	Shoup et al., "Epitaxial Thin Film Growth of Lanthanum and Neodymium Aluminate Films on Roll-Textured Nickel Using a Sol-Gel Method", Journal of the American Ceramic Society, Vol. 81, No. 11, November 1998, pp-3019-3021.
	AUUU	Smith et al., "High Critical Current Density Thick MOD-Derived YBCO Films", IEEE TRANSACTIONS ON APPLIED SUPERCONDUCTIVITY, Vol. 9, No. 2, June 1999, pp 1531-1534.
	AVVV	Tanaka et al., "Improvement of YBa <sub>2</sub> Cu <sub>3</sub> O <sub>x</sub> Single-Crystal Surface by Chemical Etching", Jpn. J. App. Phys. Vol. 38 (1999) pp L731-L733, Part 2, No. 7A, 1 July 1999.

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